

L Number	Hits	Search Text	DB	Time stamp
-	0	(h011021/\$.ipc. and (work or susceptor) and conduct\$4 and insulat\$4 and ((silicon adj carbide) or titanium)).CCLS.	JPO; DEFWENT	2002/07/25 13:43
-	1126	h011021/\$.ipc. and (work or susceptor) and conduct\$4 and insulat\$4 and ((silicon adj carbide) or titanium)	USPAT; US-PGPUB	2002/06/17 16:43
-	96	(:011021/\$.ipc. and (work or susceptor) and conduct\$4 and insulat\$4 and ((silicon adj carbide) or titanium)) and (uv or (:ultra adj violet))	USPAT; US-PGPUB	2002/06/17 16:38
-	117	(h011021/\$.ipc. and (work or susceptor) and conduct\$4 and insulat\$4 and ((silicon adj carbide) or titanium)) and static and gas	USPAT; US-PGPUB	2002/06/17 16:39
-	7	h011021/\$.ipc. and (work or susceptor) and conduct\$4 and insulat\$4 and ((silicon adj carbide) or titanium)	JPO; DEFWENT	2002/06/17 16:51
-	7	h011021/\$.ipc. and (work or susceptor or pedestal) and conduct\$4 and insulat\$4 and ((silicon adj carbide) or titanium)	JPO; DEFWENT	2002/06/17 16:52
-	543	h011021/\$.ipc. and (work or susceptor or pedestal) and conduct\$4 and insulat\$4	JPO; DEFWENT	2002/06/17 16:53
-	120	h011021/\$.ipc. and (work or susceptor or pedestal) and conduct\$4 and insulat\$4 and (silicon or titanium)	JPO; DEFWENT	2002/06/17 17:02
-	18	h011021/\$.ipc. and ((work adj table) or susceptor or pedestal or (work adj holder)) and conduct\$4 and insulat\$4 and (silicon or titanium)	JPO; DEFWENT	2002/06/17 17:39
-	528	h011021/\$.ipc. and ((work adj table) or susceptor or pedestal or (work adj holder)) and conduct\$4	JPO; DEFWENT	2002/06/17 17:42
-	227	h011021/\$.ipc. and ((work adj table) or susceptor or pedestal or (work adj holder)) and (conduct\$4 or (conductive adj film)) and gas\$2	JPO; DEFWENT	2002/06/17 17:44
-	227	h011021/\$.ipc. and ((work adj table) or susceptor or pedestal or (work adj holder)) and (conduct\$4 or (conductive adj film)) and gas\$2	JPO; DEFWENT	2002/06/23 16:01
-	1	(:011021/\$.ipc. and ((work adj table) or susceptor or pedestal or (work adj holder)) and (conduct\$4 or (conductive adj film)) and gas\$2) and static	JPO; DEFWENT	2002/07/24 13:34
-	93	c03c016/\$.ipc. and ((work adj table) or susceptor or pedestal or (work adj holder)) and (conduct\$4 or (conductive adj film)) and gas\$2	JPO; DEFWENT	2002/06/17 17:45
-	0	c03c016/\$.ipc. and ((work adj table) or susceptor or pedestal or (work adj holder)) and (conduct\$4 or (conductive adj film)) and gas\$2 and static and ground\$3	JPO; DEFWENT	2002/06/17 18:41
-	0	(c03c016/\$.ipc. and ((work adj table) or susceptor or pedestal or (work adj holder)) and (conduct\$4 or (conductive adj film)) and gas\$2) and ground\$3 and static	JPO; DEFWENT	2002/06/17 17:57
-	9	(:03c016/\$.ipc. and ((work adj table) or susceptor or pedestal or (work adj holder)) and (conduct\$4 or (conductive adj film)) and gas\$2) and ground\$3	JPO; DEFWENT	2002/06/17 18:41
-	64	156/345.5.ccls.	USPAT; US-PGPUB	2002/06/17 18:43
-	19	156/345.5.ccls. and conduct\$3 and insulat\$3	USPAT; US-PGPUB	2002/06/17 18:44
-	34	118/\$.ccls. and ((work adj table) or susceptor or pedestal or (work adj holder)) and (conduct\$4 or (conductive adj film)) and gas\$2 and static and ground\$3	USPAT; US-PGPUB	2002/07/24 14:05

-	287	118/\$.ccls. and ((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder)) same ((silicon adj carbide)or SiC or (titanium adj oxide))and gas\$2	USPAT; US-PPGPUB	2002/06/18 15:41
-	1	5304778.pn.	USPAT; US-PPGPUB	2002/06/18 10:12
-	218	118/\$.ccls. and ((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder)) same ((silicon adj carbide)or SiC or (titanium adj oxide))and gas\$2	USPAT; US-PPGPUB	2002/07/23 16:07
-	218	(118/\$.ccls. and ((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder)) same ((silicon adj carbide)or SiC or (titanium adj oxide))and gas\$2) and (conduct\$4 or gas or ground\$3)	USPAT; US-PPGPUB	2002/06/18 14:13
-	15	(156/345.\$2).ccls. and ((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder)) same ((silicon adj carbide)or SiC or (titanium adj oxide))and gas\$2	USPAT; US-PPGPUB	2002/06/18 14:03
-	11	((156/345.\$2).ccls. and ((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder)) same ((silicon adj carbide)or SiC or (titanium adj oxide))and gas\$2) not ((118/\$.ccls. and ((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder)) same ((silicon adj carbide)or SiC or (titanium adj oxide))and gas\$2) and (conduct\$4 or gas or ground\$3))	USPAT; US-PPGPUB	2002/06/18 14:04
-	1440	((tckyo adj electron).as.	USPAT; US-PPGPUB	2002/06/18 14:10
-	20	((tckyo adj electron).as.) and ((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder)) same ((silicon adj carbide)or SiC or (titanium adj oxide))and gas\$2	USPAT; US-PPGPUB	2002/06/18 14:24
-	20	((tckyo adj electron).as.) and ((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder)) same ((silicon adj carbide)or SiC or (titanium adj oxide))and gas\$2) and (conduct\$4 or gas or ground\$3)	USPAT; US-PPGPUB	2002/06/18 14:25
-	310	((tckyo adj electron).as.) and ((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder))	USPAT; US-PPGPUB	2002/06/18 14:25
-	291	((tckyo adj electron).as.) and ((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder))) and (conduct\$4 or gas or ground\$3)	USPAT; US-PPGPUB	2002/06/18 14:48
-	20	((tckyo adj electron).as.) and ((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder))) and conduct\$4 and ground\$3 and static	USPAT; US-PPGPUB	2002/07/24 10:46
-	20	((tckyo adj electron).as.) and ((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder))) and conduct\$4 and ground\$3 and static) not electrostatic	USPAT; US-PPGPUB	2002/06/18 14:54
-	0	h011021/\$.ipc. and ((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder)) and conduct\$3 and static and ground\$2	JPO; DERWENT	2002/06/18 17:23
-	42	h011021/\$.ipc. and ((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder)) and conduct\$3 and ground\$2	JPO; DERWENT	2002/06/18 15:25

6	h011021/\$.ipc. and ((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder)) and conduct\$3 and ground\$2 and (static or charge)	JPO; DEFWENT	2002/06/18 15:37
1	6.94712.pn.	JPO; DEFWENT	2002/06/18 15:38
1	6.94712.pn.	USPAT; US-PPGPUB	2002/06/18 15:38
164	118/\$.ccls. and ((work adj table) or susceptor or pedestal or (work adj holder) and (conduct\$4 or (conductive adj film),and gas\$2 and (static or charge) and ground\$3	USPAT; US-PPGPUB	2002/06/18 15:45
34	118/\$.ccls. and ((work adj table) or susceptor or pedestal or (work adj holder) and (conduct\$4 or (conductive adj film)) and gas\$2 and static and ground\$3	USPAT; US-PPGPUB	2002/06/18 15:49
130	(118/\$.ccls. and ((work adj table) or susceptor or pedestal or (work adj holder) and (conduct\$4 or (conductive adj film)) and gas\$2 and (static or charge) and ground\$3) not (118/\$.ccls. and ((work adj table) or susceptor or pedestal or (work adj holder) and (conduct\$4 or (conductive adj film)) and gas\$2 and static and ground\$3)	USPAT; US-PPGPUB	2002/06/18 16:32
109	(118/\$.ccls. and ((work adj table) or susceptor or pedestal or (work adj holder) and (conduct\$4 or (conductive adj film)) and gas\$2 and (static or charge) and ground\$3) not (118/\$.ccls. and ((work adj table) or susceptor or pedestal or (work adj holder) and (conduct\$4 or (conductive adj film)) and gas\$2 and static and ground\$3)) and film	USPAT; US-PPGPUB	2002/06/18 16:33
45	(118/\$.ccls. and ((work adj table) or susceptor or pedestal or (work adj holder) and (conduct\$4 or (conductive adj film)) and gas\$2 and (static or charge) and ground\$3) not (118/\$.ccls. and ((work adj table) or susceptor or pedestal or (work adj holder) and (conduct\$4 or (conductive adj film)) and gas\$2 and static and ground\$3)) and conductiv\$2 with film	USPAT; US-PPGPUB	2002/06/18 16:35
45	((118/\$.ccls. and ((work adj table) or susceptor or pedestal or (work adj holder) and (conduct\$4 or (conductive adj film)) and gas\$2 and (static or charge) and ground\$3) not (118/\$.ccls. and ((work adj table) or susceptor or pedestal or (work adj holder) and (conduct\$4 or (conductive adj film)) and gas\$2 and static and ground\$3)) and (conductiv\$2 with film)	USPAT; US-PPGPUB	2002/06/18 16:36
6	h110.11/\$.ipc. and ((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder)) and conduct\$3 and (static or charge) and ground\$2	JPO; DEFWENT	2002/06/18 17:25
32	118/\$.ccls. and ((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder)) same ((silicon adj carbide)or SiC or (titanium adj oxide))and gas\$2 and (charge or static)	USPAT; US-PPGPUB	2002/06/18 17:56
104	((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder)) same ((silicon adj carbide)or SiC or (titanium adj oxide))and gas\$2 and (charge or static)and (vacuum or exhaust)and conduct\$3	USPAT; US-PPGPUB	2002/06/18 18:05

57	((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder)) same ((silicon adj carbide) or SiC or (titanium adj oxide)) and gas\$2 and charge or static) and (vacuum or exhaust) and conduct\$3 and ground\$2	USPAT; US-PGPUB	2002/06/18 18:06
1	6106630.pn.	USPAT; US-PGPUB	2002/07/23 13:12
1	5879450.pn.	USPAT; US-PGPUB	2002/07/23 16:08
0	h011021/.ipc. and (work or susceptor or pedestal) with conduct\$4 with (film or layer) and dechuck\$4	JPO; DEFENT	2002/07/23 16:27
0	(h011021/.ipc. and (work or susceptor or pedestal) with conduct\$4 with (film or layer)) and dechuck\$4	JPO; DEFENT	2002/07/23 16:29
302	h011021/.ipc. and (work or susceptor or pedestal) with conduct\$4 with (film or layer)	JPO; DEFENT	2002/07/23 16:30
286	shull:J1/.ipc. and (work or susceptor or pedestal) with conduct\$4 with (film or layer)) and @ad<20000522	JPO; DEFENT	2002/07/24 13:48
284	(h011021/.ipc. and (work or susceptor or pedestal) with conduct\$4 with (film or layer)) and @ad<20000522	JPO; DEFENT	2002/07/24 16:29
1..	((113c016/.ipc. and (work or susceptor or pedestal) with conduct\$4 with (film or layer)) and @ad<20000522) not ((h011021/.ipc. and (work or susceptor or pedestal) with conduct\$4 with (film or layer)) and @ad<20000522)	JPO; DEFENT	2002/07/24 16:30
37	((tokyo adj electron).as.) and (susceptor or pedestal or work or substrate) and conduct\$4 and ground\$3 and static	USPAT; US-PGPUB	2002/07/24 16:52
203	118/.ccls. and (work or susceptor or pedestal or substrate) and conduct\$4 and static and ground\$3	USPAT; US-PGPUB	2002/07/24 17:54
2	"10070151"	JPO; DEFENT	2002/07/24 17:46
2	"10116888"	JPO; DEFENT	2002/07/24 17:49
41	(c03c016/.ipc. and (work or susceptor or pedestal) with conduct\$4 with (film or layer)) and @ad<20000522	JPO; DEFENT	2002/07/24 17:54
2	"02043722"	JPO; DEFENT	2002/07/24 12:55
168	156/345.51.ccls.	USPAT; US-PGPUB	2002/07/24 13:14
151	156/345.51.ccls. and @ad<20000522	USPAT; US-PGPUB	2002/07/24 13:14
100	(156/345.51.ccls. and @ad<20000522) and conduct\$4	USPAT; US-PGPUB	2002/07/24 13:20
51	(156/345.51.ccls. and @ad<20000522) and conduct\$4 and ground\$3	USPAT; US-PGPUB	2002/07/24 13:20
43	(361/010-224 ccls.) and (susceptor or pedestal or work or substrate) and conduct\$4 and gas\$2 and static and ground\$3	USPAT; US-PGPUB	2002/07/24 13:20
323	(work or susceptor or pedestal or (substrate adj holder)) with (conduct\$4 or (conductive adj (film or layer))) and gas\$2 and static and ground\$3	USPAT; US-PGPUB	2002/07/24 14:14
299	((work or susceptor or pedestal or (substrate adj holder)) with (conduct\$4 or (conductive adj (film or layer))) and gas\$2 and static and ground\$3) and @ad<20000522	USPAT; US-PGPUB	2002/07/24 14:15
1	4691230.pn.	USPAT; US-PGPUB	2002/07/25 12:11
1	4873549.pn.	USPAT; US-PGPUB	2002/07/25 12:11